

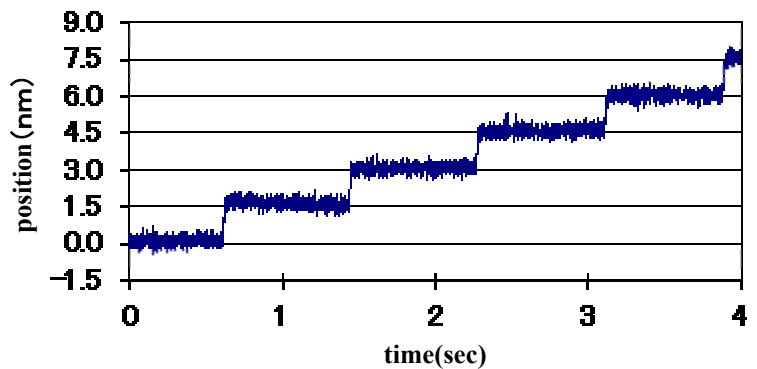
NAPS[®] (NAⁿo Positioning System)

Fine positioning system MT4200 Series

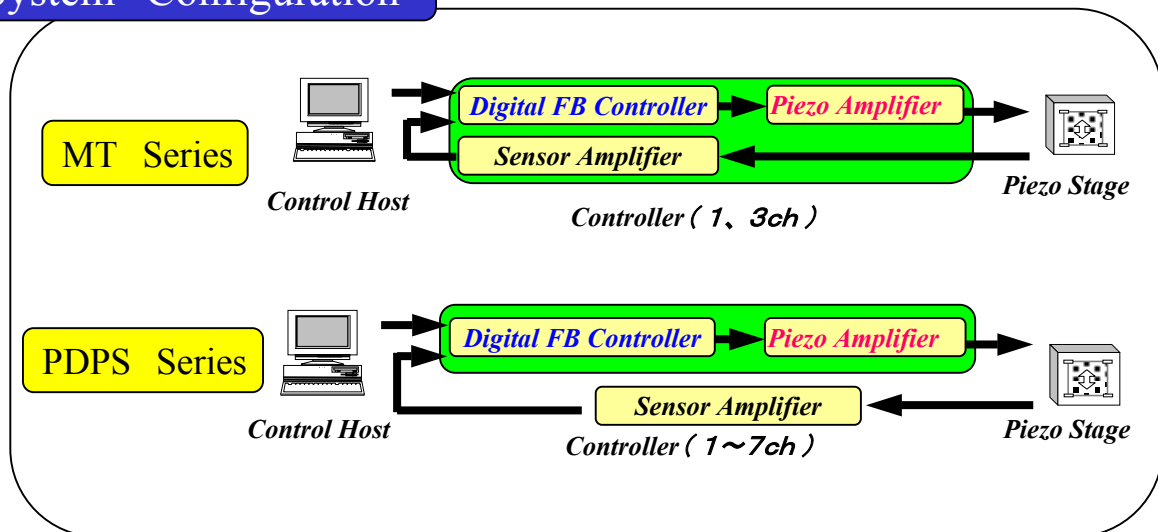
High resolution (Less than 1nm)



Driving sample (resolution : 1.5nm)



System Configuration



Applications

- Fine positioning for MR head / HD media inspections
- Fine adjustment for LCD steppers
- Fine positioning for semiconductor-related inspections

NAPS[®] (NAno Positioning System)

Fine positioning system

Fine Positioning Piezo Controller :MT4200

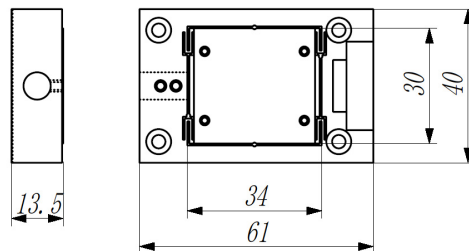
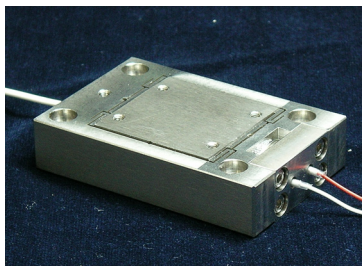
Specifications

No. of control axes	1~3 axes
Dimensions	120(W) X 100(H) X 270(D)mm
Positioning control input(analog)	0~10V
Positioning control input(digital)	RS-232C
Control linearity	Less than $\pm 0.1\%$
Control resolution	Less than 3mV
Positioning complete status output	2 levels(open collector output)can be set at time of shipment

Fine Positioning Piezo Stage :PSS1015

Specifications

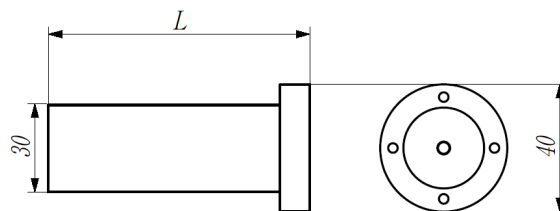
Dimensions	61.0(L) X 40.0(W) X 13.5(H)mm
Stroke	15 μ m
Resolution	Less than 1nm
Resonance frequency	3kHz or higher
Pitching	Less than 1sec
Yawing	Less than 1sec



Fine Positioning Piezo Positioner :SRB,SRT series

Specifications

	SRB(T)3020	SRB(T)3040	SRB(T)3060	SRB(T)3080
Dimensions(Φ xL)	40x80mm	40x100mm	40x120mm	40x140mm
Stroke	15 μ m	30 μ m	45 μ m	60 μ m
Resolution	Less than 2nm	Less than 4nm	Less than 6nm	Less than 8nm



NIHON CERATEC CO.,LTD.

7-12-18,Daiichi Ginza Bldg.3F,Ginza,Chuo-ku,Tokyo,104-0061 Japan TEL. +81-3-5565-6262 FAX. +81-3-5565-6270
 2700 Augustine, Suite 101, Santa Clara, CA 95054, USA TEL. +1-408-567-0347 FAX. +1-408-567-0357
<http://www.ceratech.co.jp/> E-mail : piezo-electric@ceratech.co.jp